

Abstract

Improved is the yield of polycrystalline silicon having a desired particle size and sufficiently reduced is an amount of generated fine powder of polycrystalline silicon. A crushing device (1) for polycrystalline silicon (S) includes a driving section (30) configured to sandwich the polycrystalline silicon (S) between the first member (10) and the second member (20) to crush the polycrystalline silicon (S), and the driving section (30) drives at least one of the first member (10) and the second member (20) so that a shortest distance (D1) between the first member (10) and the second member (20) becomes not less than 17 mm and not more than 30 mm.

15

(Figure 1)